

Modules of the 2025 course

Topics covered	No	Lecture/Date
VAT Photo polymerization (history) – DLP printer – light engine – part I	5	20.03.2025
DLP printer – chemical components in a photoresin – role of oxygen – CLIP method– part II	6	27.03.2025
Tomographic Volumetric Additive Manufacturing (TVAM): principles and applications	7	03.04.2025
Two photon Polymerization : nanoscale printing	8	10.04.2025
Two photon Polymerization : applications	9	17.04.2025
EASTER BREAK		22.04.2025
Prof. Paul Dalton, University of Oregon: Met Electro Writing (nanoscale)	10	1.05.2025
Gari Arutinov, Holst Center for AM: Mass transfer of microcomponents	11	08.05.2025
Julian Schneider: Scrona	12	15.05.2025
Patrizia Richner: Sonova (hearing aids). //	13	22.05.2025
Design Competition		

QUIZZ #2

Although the wavelength is 780nm,
It is possible to make structures
With size 65 nm !!

By adjusting the dose i.e

*Intensity * exposure times*

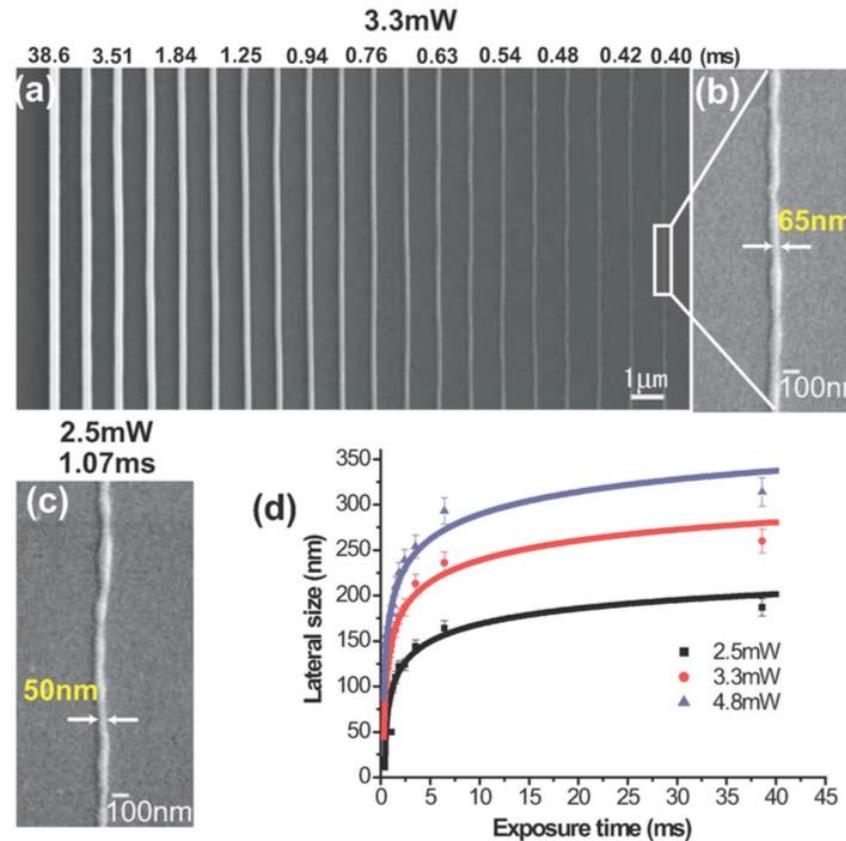
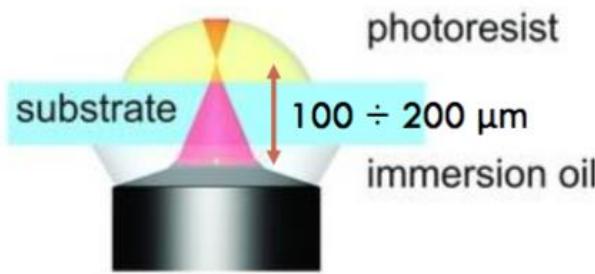
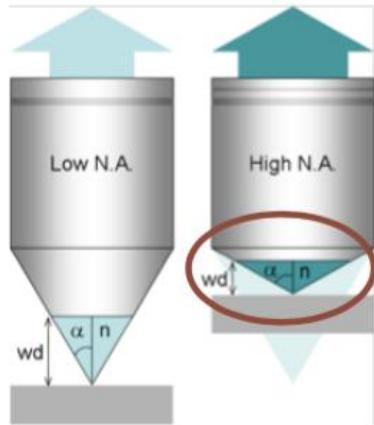


FIG. 2. (Color online) (a) SEM images of photocured polymer lines obtained using a laser power of 3.3 mW, after various exposure times. (b) Enlarged image of a line fabricated with a laser power of 3.3 mW and an exposure time of 0.4 ms. (c) A polymer line with a width of 50 nm. (d) LSR -vs exposure time under different laser powers (lines are calculated results).

Height Limitation of 3D structures



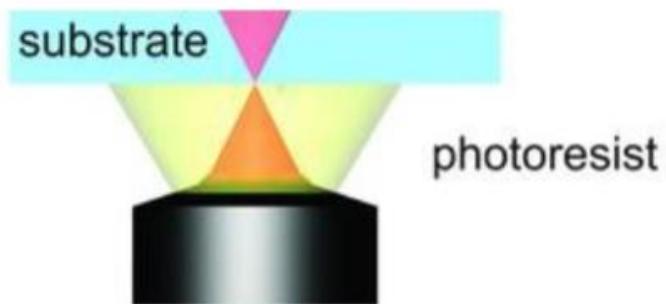
E.G.: Zeiss Objective Plan-Apochromat 63x/1.40 Oil DIC

- $M=63x$
- $NA=1.4$
- $WD=190 \mu m$

Max height $\sim 10 \mu m$

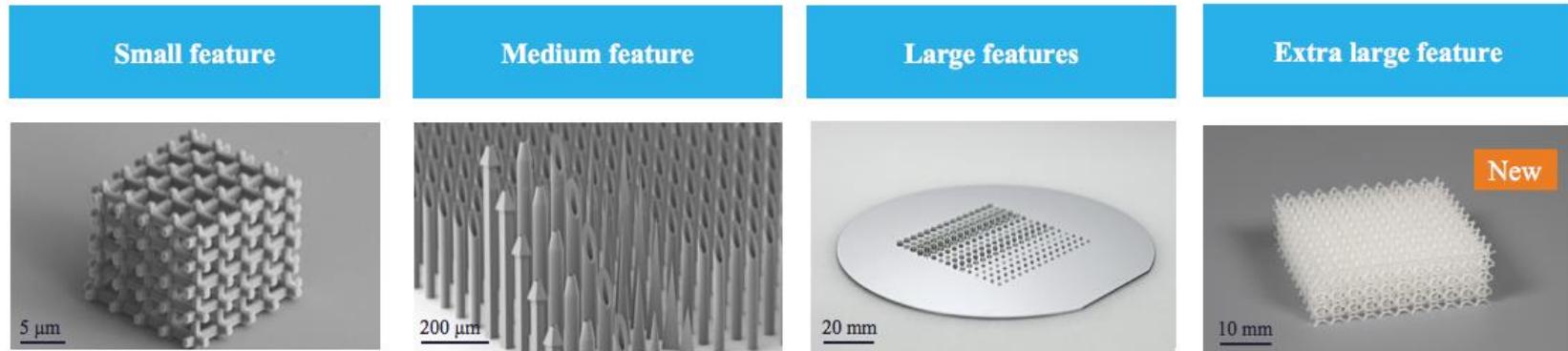
DW: Working distance of the microscope objective i.e
The distance between the objective and the focal distance

- DIP-IN



Only photoresists with matched n
can be used

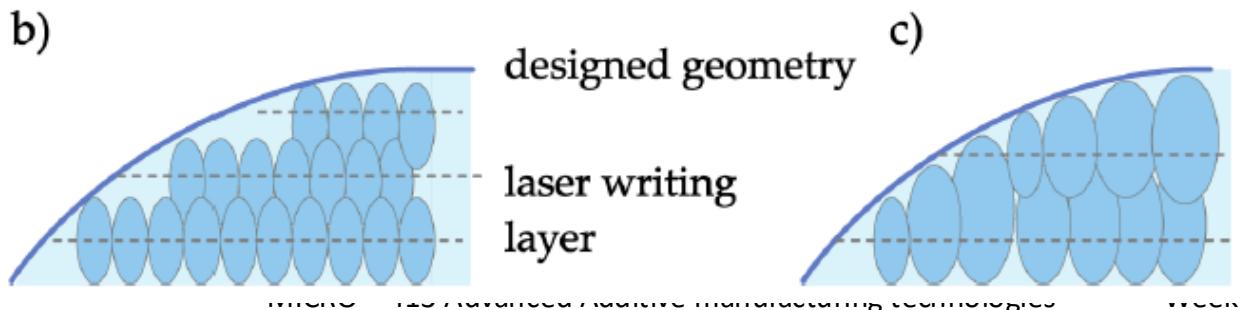
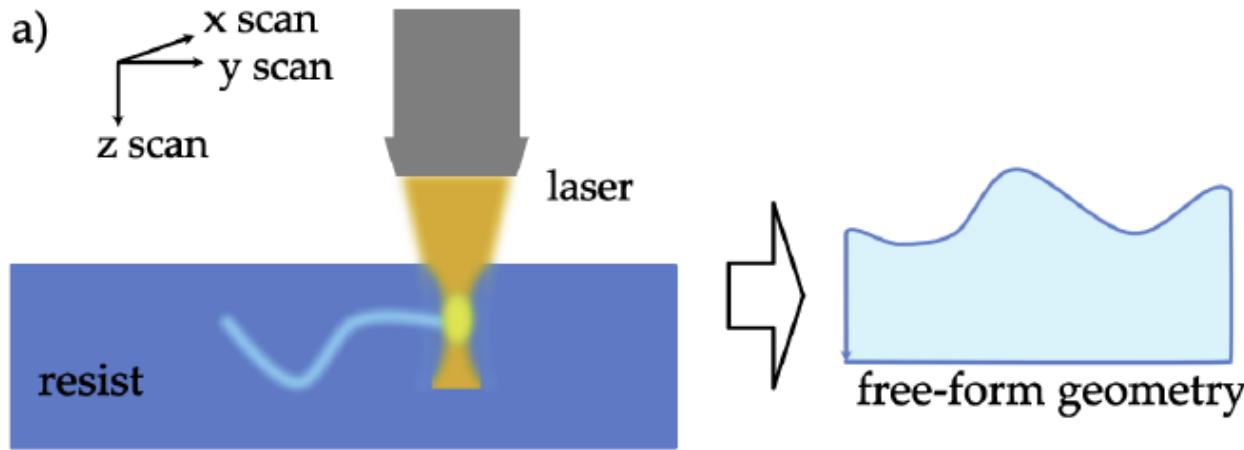
Dip-in mode



	Small feature	Medium feature	Large features	Extra large feature
Magnification NA	63x 1.4	25x 0.8	10x 0.3	5x 0.16
Calibrated print field diameter	270 μm	700 μm	1,750 μm	3,200 μm
Working distance	360 μm	380 μm	2,600 μm	18,500 μm
Scan speed (max.)	100 mm/s	250 mm/s	625 mm/s	1,250 mm/s
Slicing range (typical)	0.1 – 0.8 μm	0.5 – 3 μm	2 – 10 μm	5 – 100 μm

Two-photon polymerization (2PP)

Two-photon grayscale lithography (2GL)



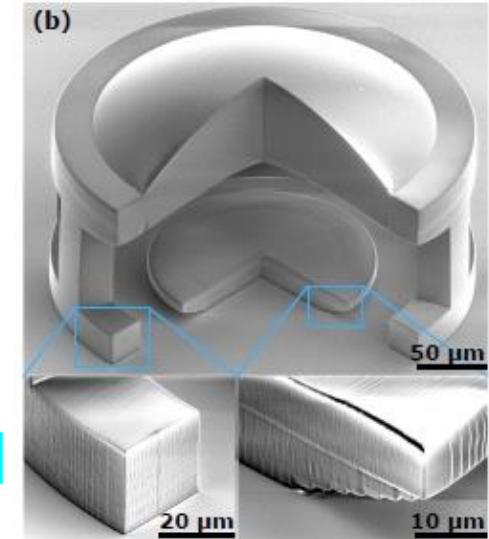
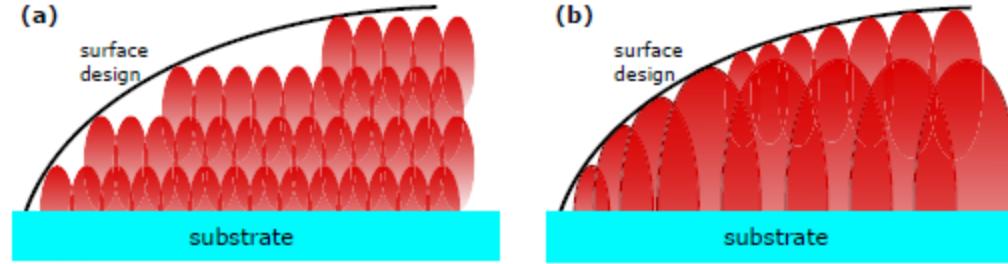
2GL on Aspherical Singlet and Doublet



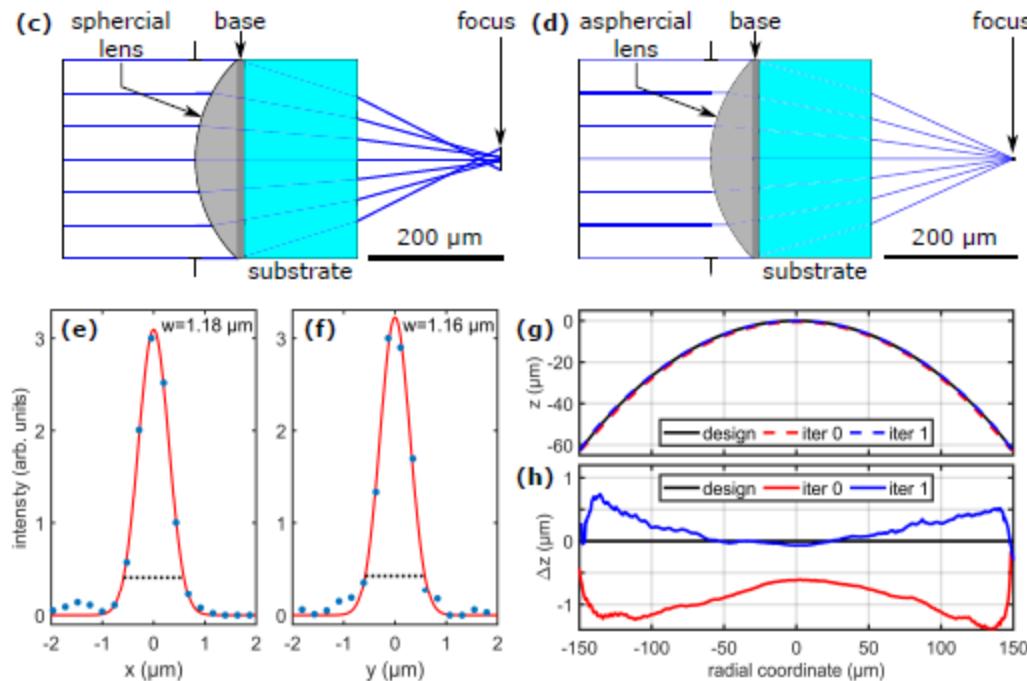
Complex aspherical singlet and doublet microoptics by grayscale 3D printing

LEANDER SIEGLE,^{*} SIMON RISTOK, AND HARALD GIESSEN

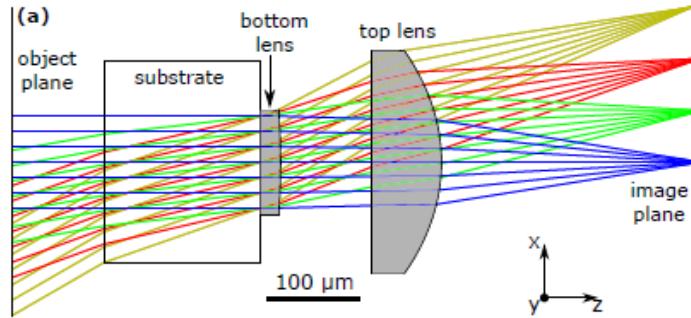
4th Physics Institute and Research Center SCoPE, University of Stuttgart, Pfaffenwaldring 57, 70569 Stuttgart, Germany
^{*}l.siegle@pi4.uni-stuttgart.de



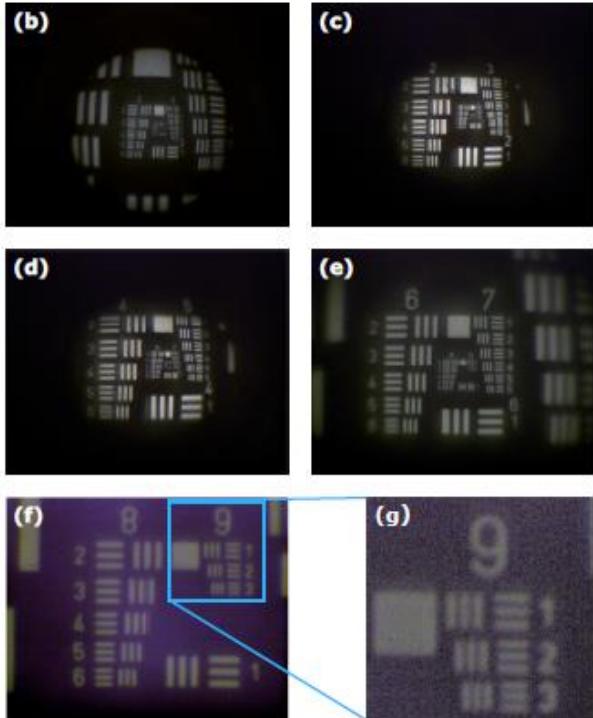
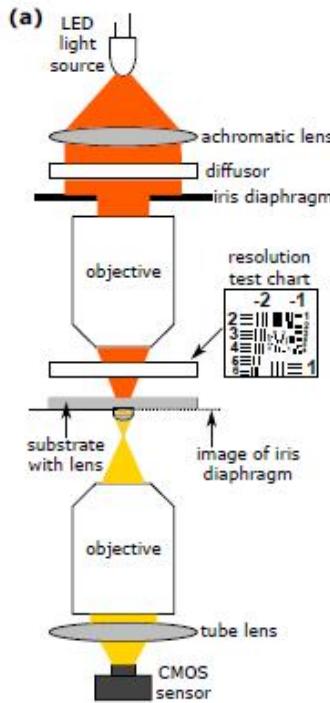
2GL on Aspherical Singlet and Doublet



2GL on Aspherical Singlet and Doublet



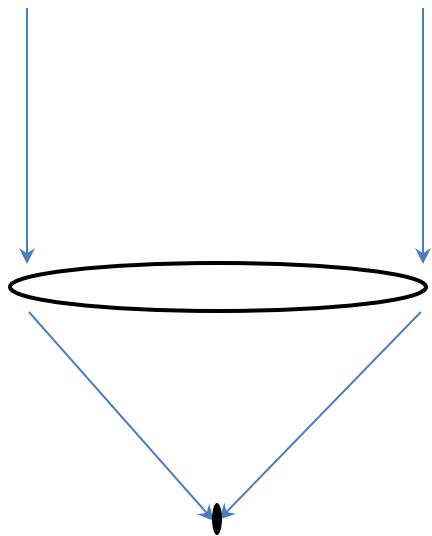
field of view of 60°
deviations 20 nm for the bottom lens
deviations 100 nm for the larger top lens
resolution 645 lp/mm



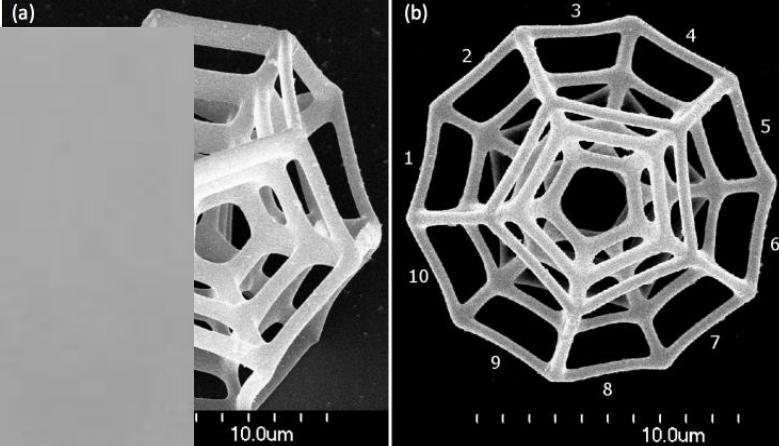
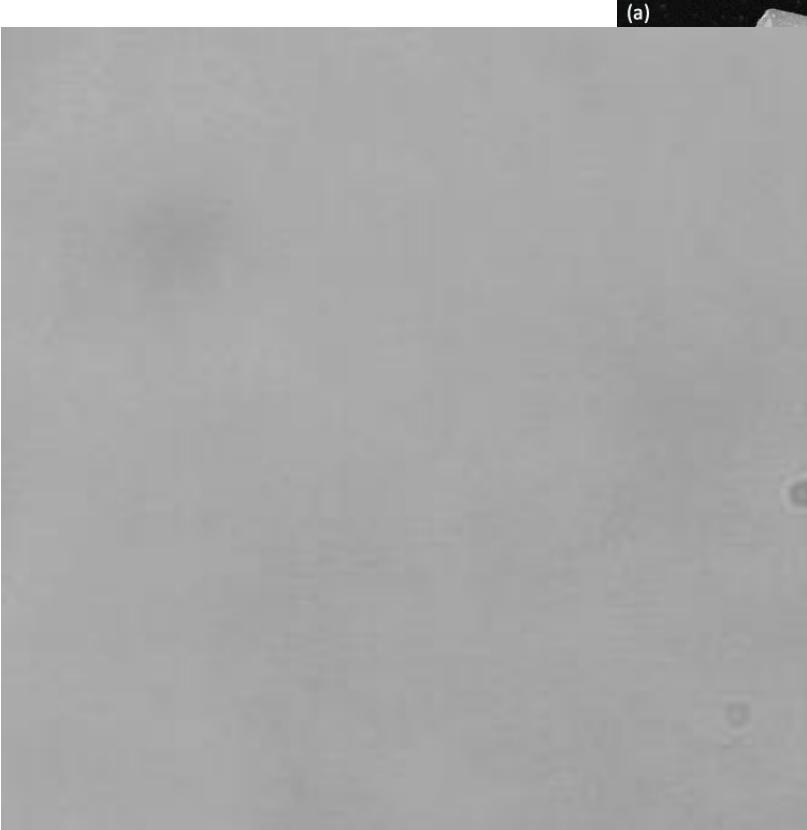
How to increase printing speed ?

Holographic multi-focus 3D two-photon polymerization
with real-time calculated holograms – Optics Express 2014

EPFL



Single focus



Fabricated by 550
projections giving each 5
Foci.

1 into

This can be generated by
and for example
Advanced Additive manufacturing technologies

Example: bio-printing

5 ms exposure, 3 mW/foci \rightarrow 200 Hz

750 foci \rightarrow 2.2 W



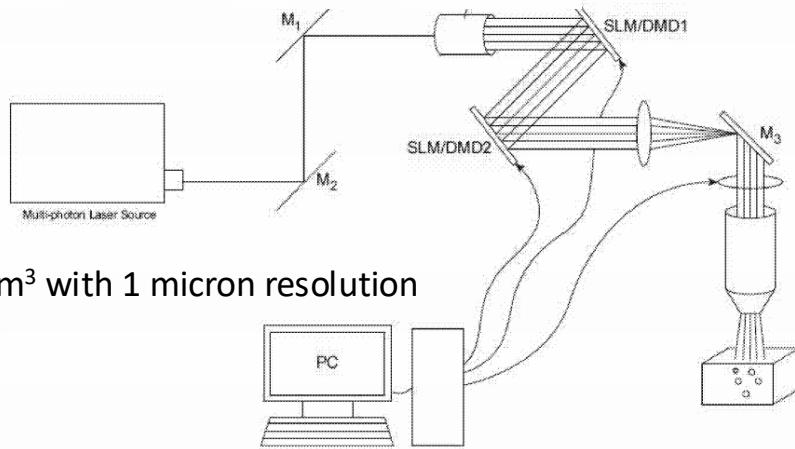
(19) **United States**
(12) **Patent Application Publication**
MATHEU

EPFL

(54) **METHODS AND SYSTEMS FOR PRINTING BIOLOGICAL MATERIAL**

(71) **Applicant: Prellis Biologics, Inc., San Francisco, CA (US)**

(52)



Time to print 1 cm³ with 1 micron resolution

$$fab\ time = f \cdot n_{voxels} / \#voxels/sec$$

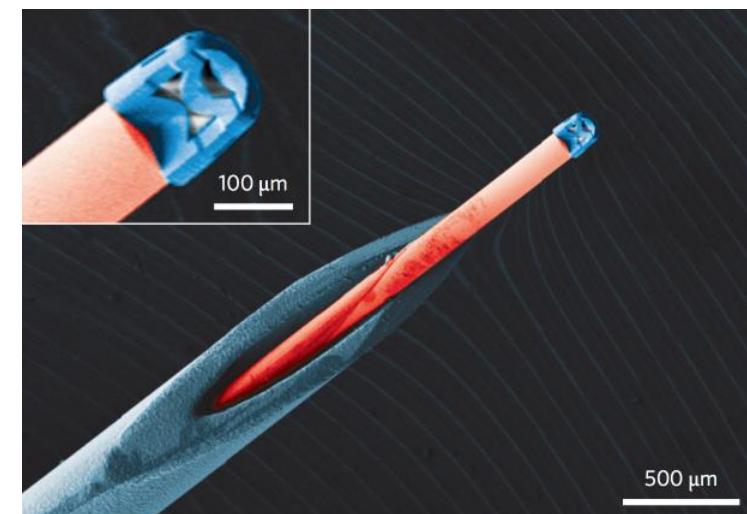
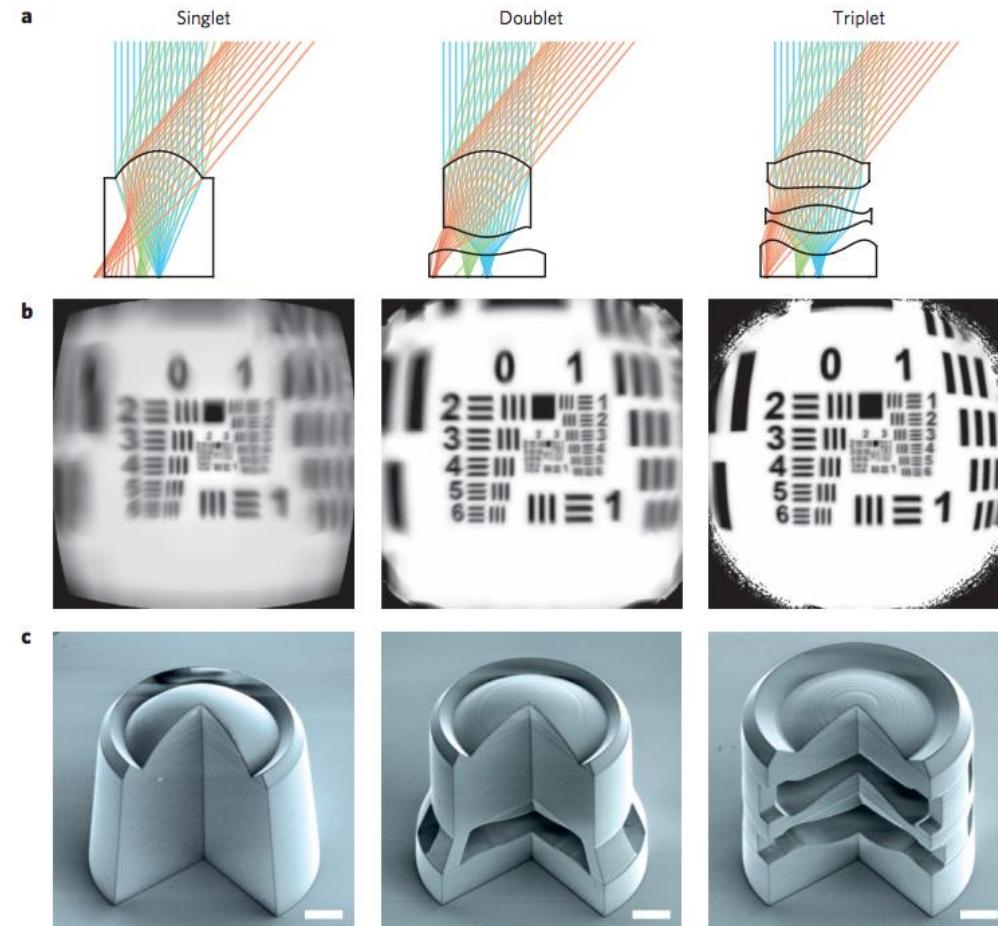
Fill factor 1%

15%

18.5 h

11.5 days

Two-photon direct laser writing of ultracompact multi-lens objectives



Transparent polymer material

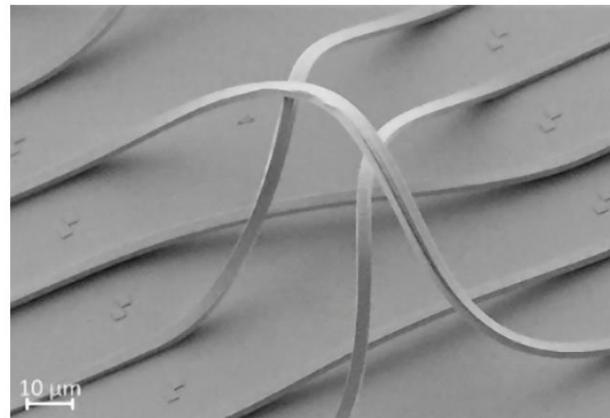
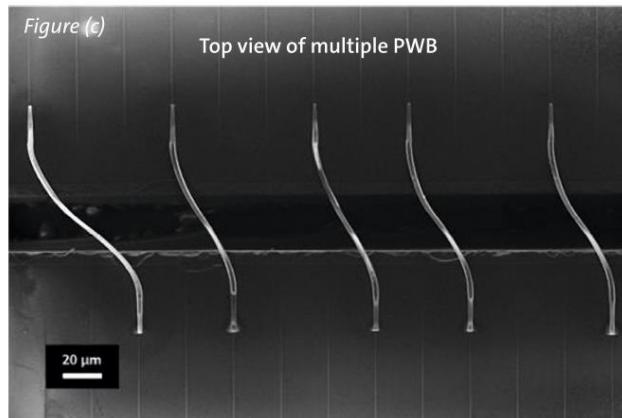
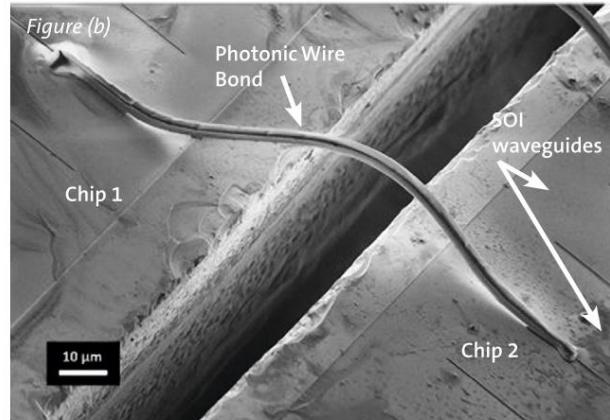
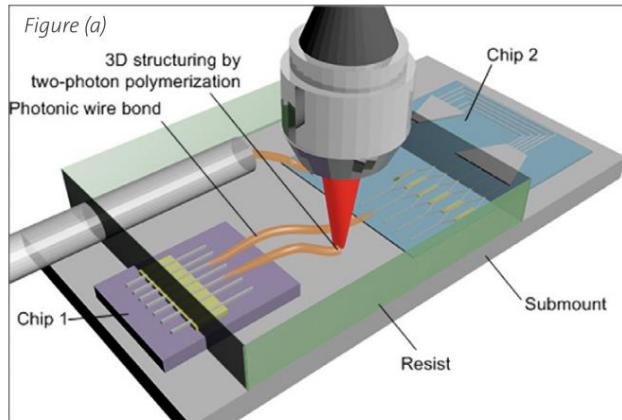
manufacturing technologies

Week 9

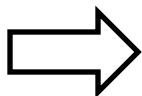
Photonic Wire bonding

Vol. 20, No. 16 / OPTICS EXPRESS 2012

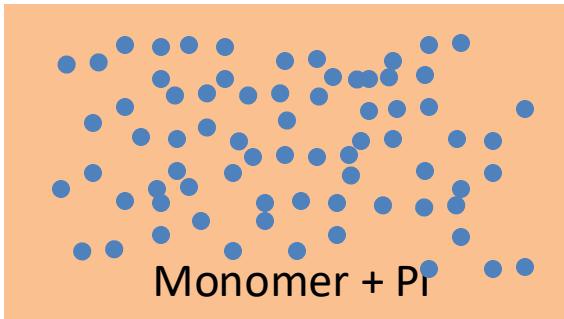
EPFL



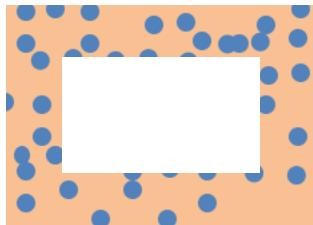
2 Photon Polymerization : glass



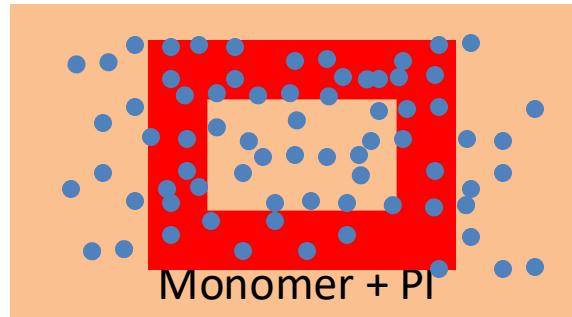
Disperse silica nano particles (30% volume)



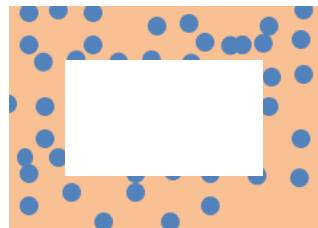
Silicate nanoparticle embedded in
Polymerized resin



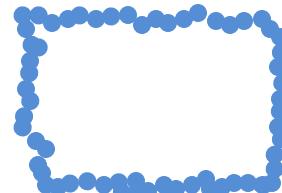
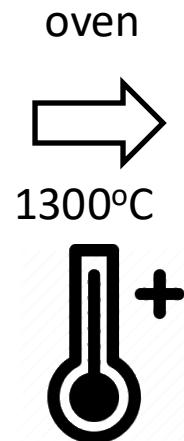
Illuminate
to polymerize



2 Photon Polymerization : glass

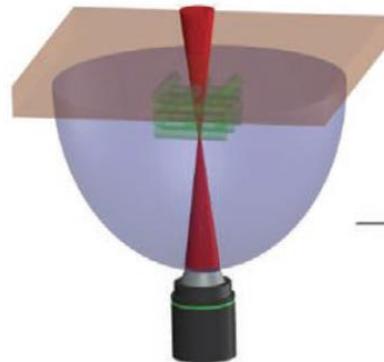


"green body"

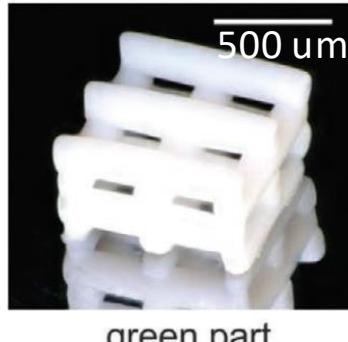


The silica particles sinter and the polymer are vaporized by the heat
Leaving only the merged silicate particles

a



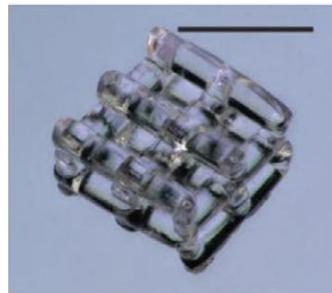
b



binding
00 °C

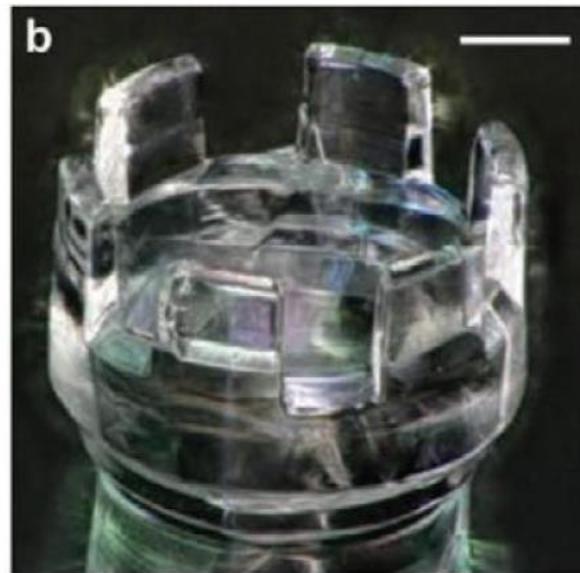


Sintering
1300 °C

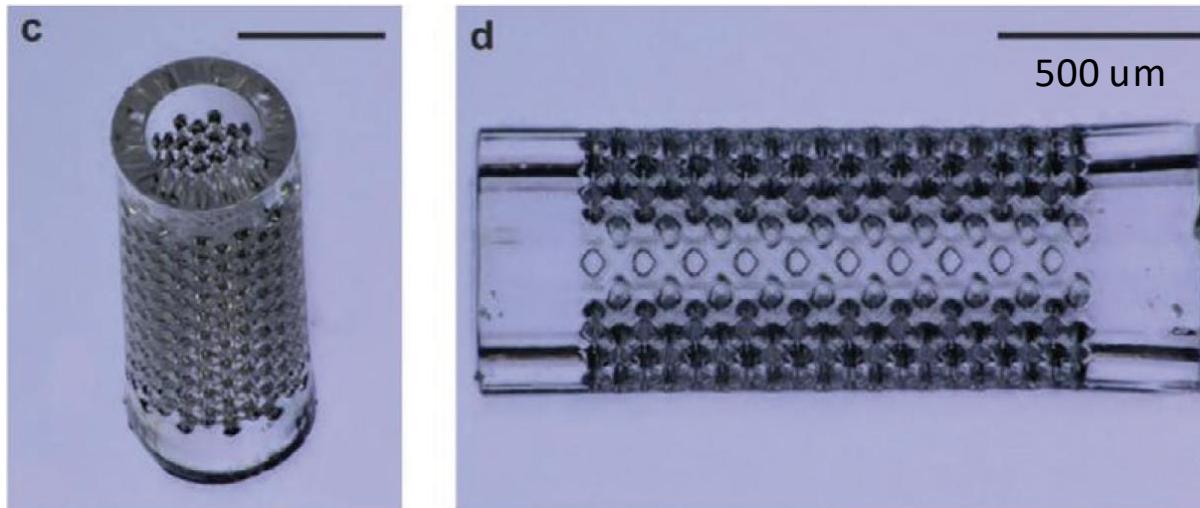


Direct laser writing=2 Photon Polymerization

Micro glass prints

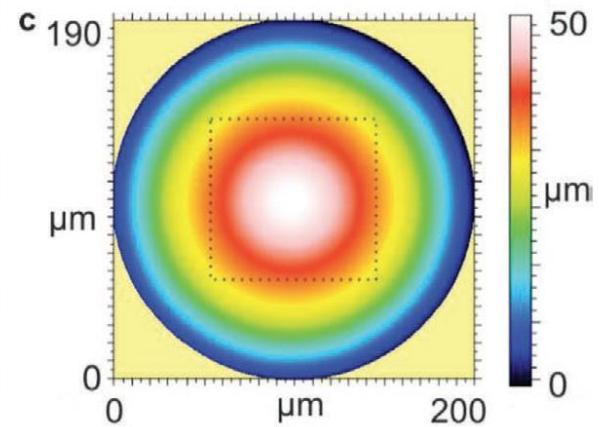
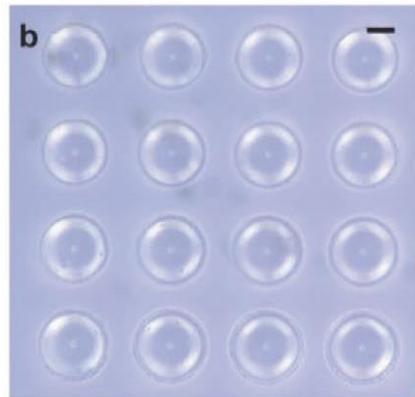
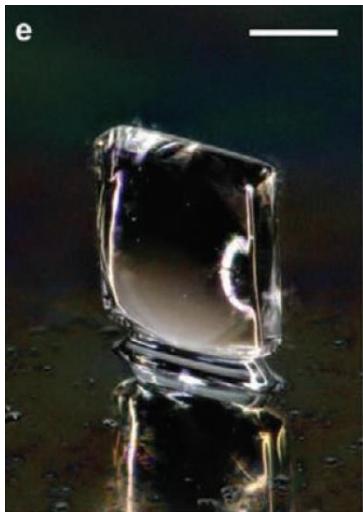


Slicing 5 μm, hatching 1 μm, scan speed 100 mms⁻¹



Micro filter element with 55 μm holes

Slicing 5 μm , hatching 1 μm , scan speed 100 mms^{-1}



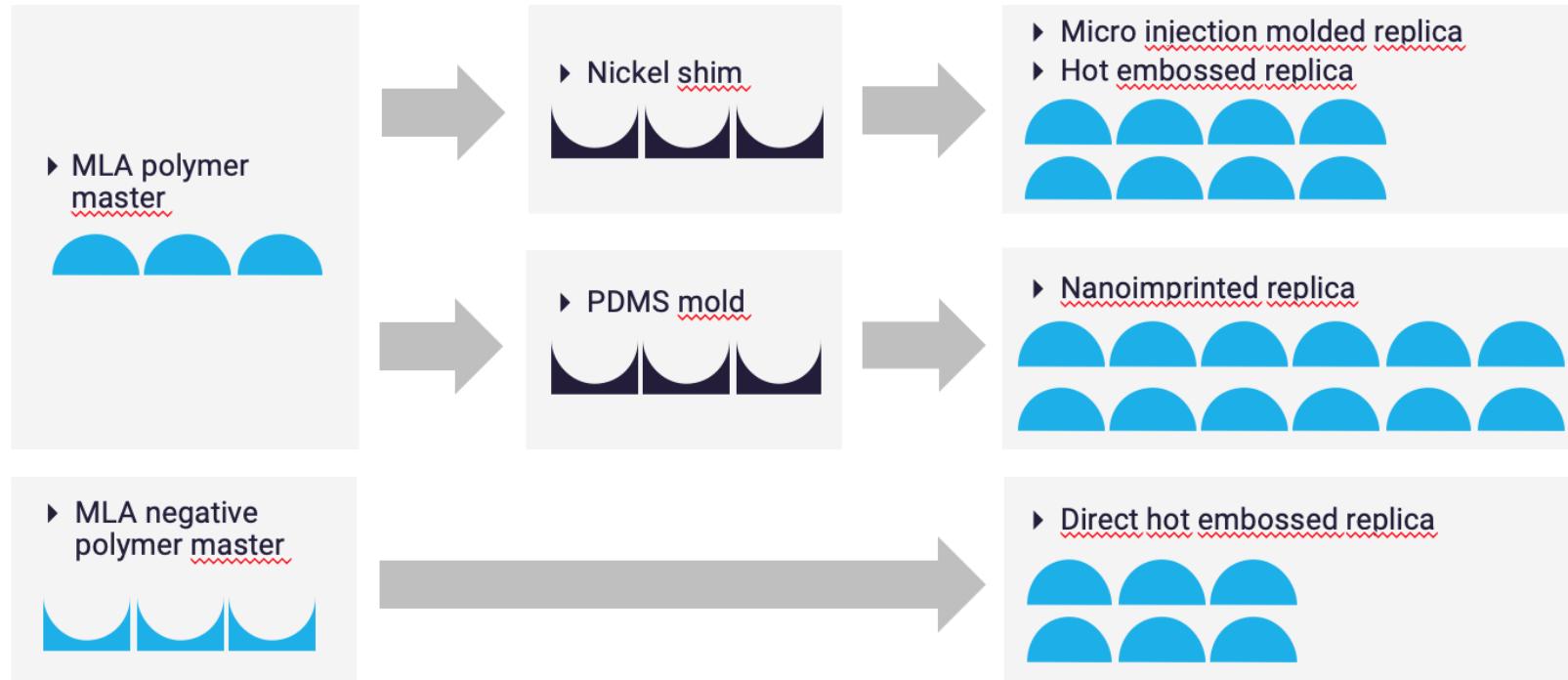
Glass micro lenses

Surface roughness $\text{Ra} \approx 6.1 \text{ nm}$

High precision parts for replication

Replication processes

From polymer master to small series production



2-photon
Printer
By Nanoscribe

At Cmi
BM building

